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Johr et al.

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10/034800
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U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
MP	AA	5872630	2/1999	Johr et al	356	369	
	AB	5666201	9/1997	Johr et al	356	369	
	AC	5706212	1/1998	Thompson et al	364	525	
	AD	6320657	11/2001	Aspner et al	356	369	
	AE	6134012	10/2002	Aspner et al	356	369	
	AF	5973787	10/1999	Aspner et al	356	369	
	AG	5877859	3/1999	Aspner et al	356	364	
	AH	5373359	12/1994	Woodham et al	356	328	
	AI	5504582	4/1996	Johr et al	356	369	
	AJ	5521706	3/1996	Green et al	356	369	
MP	AK	5329357	7/1994	Bernoux et al	356	369	

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MP	AR	WC C1/90687 A2 (Thermal wave)						
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KP	AA	5581356	12/1996	Chen et al	357	365	
A	AB	4772104	9/1998	Duhrer	358	403	
	AC	4961634	10/1990	Chipman et al	358	403	
	AD	5946098	8/1999	Jahr et al	358	364	
	AE	6118537	9/2000	Jahr et al	358	364	
	AF	6100481	8/2000	Jahr et al	358	364	
	AG	6141102	10/2000	Jahr et al	356	364	
	AH	5963325	10/1999	Jahr et al	358	364	
	AI	6084674	7/2000	Jahr et al	358	364	
	AJ	6084675	7/2000	Hertzinger et al	358	364	
KP	AK	584495	10/1895	ABBE			

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Form PTO-1449 REV. 1-64	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO.	SERIAL NO.
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<u>108</u>	AA	<u>4556292</u>	<u>12/1985</u>	<u>McPhyrrick et al</u>	<u>350</u>	<u>394</u>	
<u>108</u>	AB	<u>3817624</u>	<u>6/1974</u>	<u>Martin</u>	<u>350</u>	<u>286</u>	
<u>108</u>	AC	<u>2447828</u>	<u>8/1948</u>	<u>West</u>	<u>—</u>	<u>—</u>	
<u>108</u>	AD	<u>4176951</u>	<u>12/1974</u>	<u>Robert et al</u>	<u>356</u>	<u>33</u>	
	AE	<u>4179217</u>	<u>12/1979</u>	<u>Robert et al</u>	<u>356</u>	<u>33</u>	
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AL			<u>None</u>				
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	AS			<u>None</u>

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147 "Regression Calibration Method For Rotating Element Ellipsometers", which appeared in Thin Film Solids, Vol. 234 in 1993.

148 "Data Analysis for Spectroscopic Ellipsometry", Jellison Jr., Thin Film Solids, 234, (1993).

149 "Automated Rotating Element Ellipsometers: Calibration, Operation, and Real-Time Applications", Collins, Rev. Sci. Instrum. 61(8), August 1990.

150 "Systematic Errors in Rotating-Compensator Ellipsometry" Kleim et al., J. Opt. Soc. Am./Vol. 11, No. 9, Sept 1994.

151 "A New Calculus For The Treatment Of Optical Systems", Jones, J.O.S.O., Vol. 31, (July 1941).

152 "Mueller Matrix Ellipsometry With Imperfect Compensators", Hauge, J. Opt. Soc. Am., Vol. 68, No. 11, (Nov. 1978).

153 Papers by Schubert and Schubert et al.: which describe "Generalized Ellipsometry" are disclosed as they provide insight as how to Mathematically treat depolarizing Elements are:

154 "Polarization Dependent Parametes of Arbitrary Anisotropic Homogeneous Epitaxial Systems", Phys. Rev., B 53, (1996);

155 "Generalized Transmission Ellipsometry For Twisted Biaxial Dielectric Media: Application to Chiral Liquid Crystals", J. Opt. Soc. Am A, Vol 13, No. 9 (1996); and

156 "Extension of Rotating-Analyzer Ellipsometry to Generalized Ellipsometry: Determination of the Dielectric Function Tensor From Uniaxial TiO2", J. Opt. Soc. Am. A. 13, (1996).

157 "Analysis of Specular and Textured SnO2:F Films by High Speed Four-Parameter Stokes Vector Spectroscopy", Rovira & Collins, J. App. Phys., Vol. 85, No. 4, (1999).